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Advances in Nanocarbon Metals: Fine Structure

prepared by Lourdes Salamanca-Riba

University of Maryland 1244 Jeong H. Kim Engineering Building College Park, MD 20742

under contract W911NF-13-1-0058

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can incorporate large amounts of or alloy. Once the C has been remelting and resolidification. C Raman spectroscopy, and transcovetic materials. However, the	of the structure and some properties of silver, configuration (C) in a nanoscale form to alter physic incorporated into the matrix, it is highly stable Characterization of the thin film and bulk covet smission electron microscopy. Interesting proper samples always had nonuniformity of the C interest to a more uniform distribution of the C	al and mechanical properties of the base metal e and remains dispersed in the material after ics was accomplished using X-ray diffraction, erty changes were detected for the different corporation. Going forward, it is important to	
covetic, nanocarbon silver, alum	ninum, copper		

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1. Introduction

Recent advances in nanomanufacturing have made it possible for large amounts (>8 wt%) of carbon (C) to be incorporated as nanoscale C during a reaction process in molten aluminum (Al), copper (Cu), silver (Ag), and other elements. These materials, developed by Third Millennium Materials, LLC, are called "covetics". The process of conversion to covetics consists of heating the metal to a temperature above its melting point, adding C in various forms and applying a direct current to the melt while stirring. This process is a relatively simple process that produces a material with many unique and improved properties over the base metal from which it is generated. After the conversion process, the C is highly stable, despite its form not being predicted in phase diagrams, and remains dispersed in the material after remelting and resolidification. The C is bonded to the metal matrix and has an effect on several of the properties of the material.

2. Discussion

In this study we investigated the structure and some properties of Ag, Cu, and Al alloy covetics. We also deposited Cu covetic films by e-beam evaporation and pulsed laser deposition (PLD) and examined the electrical and transmittance properties of Cu covetic films compared with pure Cu films of the same thickness. The bulk samples for this investigation were obtained from Third Millennium Materials, LLC. Pieces of the bulk material were used as targets for the film deposition. The attached PowerPoint presentation (Appendix) given at a meeting at the Defense Advanced Research Projects Agency on 30 September 2014 has more details on the results for the project. The team members with their respective responsibilities are presented on slide 2 of the presentation.

We characterized the structure of the bulk covetics by X-ray diffraction (XRD) and transmission electron microscopy (TEM). No sample showed indications of any of the different allotropes of C by XRD. In TEM, however, we found localized regions of Ag and Al6061 covetics that showed weak spots in the diffraction patterns corresponding to graphitic carbon. These regions not only had crystalline graphitic spots, but also indicated a 3-dimensional epitaxial configuration with the metal host. The epitaxial relationship is $(111)_{Ag}$ (Al)//(0001)_{Graphite} and $< 1\overline{10} >_{Ag}$ (Al)// $< 11\overline{20} >_{Graphite}$. Furthermore, both Ag and Al covetics show graphitic modes in their Raman spectra indicating that C in these samples has sp2 bonding in agreement with the electron diffraction patterns and electron energy loss spectroscopy (EELS) data. Additionally, our discrete Fourier transform (DFT)—based calculations of the phonon density of states in Ag

and Al covetics with layers of graphite reproduced the Raman active modes obtained experimentally not only for the D and G peaks of graphite but also for new weak modes corresponding to Ag-(Al)-C bonding that were obtained in the Raman spectra from Ag and Al covetics. The metal-C bonds form at edges of graphene-like sheets and wherever there is a C vacancy within the graphene layer. DFT indicates bond energy of 1.2-2.2 eV/C atom. More details of the results from Ag and Al covetics can be found, respectively, in slides 5–20 and 21–31 of the Appendix. A paper on Ag covetic is ready for submission to the journal *Advanced Functional Materials*. Another paper on Al covetic is in preparation.

Cu covetic has a different structure than Ag and Al covetics. The XRD spectra from Cu covetic appear just like pure Cu. No evidence for any allotrope of C, CuO, or Cu₂O was found in any of the bulk Cu covetic samples. The electron diffraction patterns in TEM also show no evidence for any of these phases. Instead, weak spots were visible in the diffraction pattern of Cu covetic that correspond to modulations of approximately 1.6 nm along several crystallographic directions of the Cu host lattice that are visible in the images from the areas with the weak spots. The intensity of the weak spots increases with increasing C content in the local region. Results from bulk Cu covetic are presented in slides 32–39 of the Appendix.

Slides 40–56 present analysis of Raman and EELS spectra as indications of *sp2* bonding in covetics. The temperature dependence of the electrical resistivity of Ag covetic is presented in slides 57–59. It is remarkable that the conductivity of Ag covetic with 6-wt% C at room temperature is 90% that of 99.999 Ag. We believe that further improvement in the processing of covetics could give rise to even higher values of the conductivity.

Using pieces of bulk Cu covetic as targets, we deposited films by e-beam evaporation and PLD. Pairs of films were deposited at the same time where one film was deposited on silicon and one on glass substrates for further analysis of the films. For comparison, films of Cu metal (0% C) were also grown using the same conditions. The e-beam deposited films were crystalline with preferred orientation along <111>. The films were continuous with fairly flat surfaces and columnar structure. Cu covetic films deposited on glass were consistently more transparent to light than Cu films of the same thickness, indicating that C incorporation in the films assists in making the film more transparent. Furthermore, the covetic films were also more stable to the environment, as concluded from the smaller changes in resistivity with time in the Cu covetic films compared with the Cu metal films.

Our preliminary results from PLD Cu covetic films showed further improvement in the transmittance of the films compared with the e-beam deposited films, but the films had some problems with C separating from the Cu. The results from the films look very promising, although further attempts to optimize the deposition parameters are necessary to improve the performance and stability of Cu covetic films grown by PLD. Slides 60–81 present our results on Cu covetic films. We have submitted a paper on Cu covetic films for transparent electrodes for publication in the journal *Applied Physics Letters*.

3. Conclusions

In conclusion, we have obtained very interesting results of Ag, Al, and Cu covetics both in bulk and film form. Carbon in covetics changes the properties of the material. However, the samples always had nonuniformity of the C incorporation. It is important to develop a method that will give rise to more uniform distribution of the C so that a correlation between C content and properties can be obtained. Once this is achieved, the properties of covetics could be tuned by the C content and postprocessing conditions. It is also important to investigate what is the maximum C content that can be introduced in the host lattice by this method.

4. Reference

1. Shugart JV, Scherer RC, inventors; Third Millennium Metals, LLC, assignee. Metal-carbon compositions. United States patent US 8,349,759. 2013 Jan 8.

Appendix. Advances in Nanocarbon Materials: Fine Structure Final Report

This appendix appears in its original form, without editorial change.



Advances in Nanocarbon Materials: Fine Structure Final Report

Lourdes Salamanca-Riba University of Maryland September 30, 2014

Funded by DARPA/ARL under contract W911NF1310058

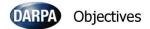
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Team Members

- Lourdes Salamanca-Riba, MSE University of Maryland Romaine Isaacs (graduate student)
 - · Structure and composition analysis of bulk and film covetics
- Liangbing Hu, MSE University of Maryland Hongli Zhu (post-doctoral fellow)
 - · Optical and electrical characterization of thin film covetics
- Maija Kukla, MSE University of Maryland Sergey Rashkeev (research fellow)
 - · DFT calculations of the structure of covetics

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- To perform a detailed investigation of the structure and bond-type of Al, Ag and Cu covetic samples that will be obtained from TM² and Cu covetic samples received from Carnegie Mellon University.
- To use e-beam deposition and PLD to fabricate Cu covetic films from the Cu covetic bulk samples.
- To use XRD, SEM, EDS, EELS, Raman and AFM to investigate the structure, morphology, composition and bond type of Al and Cu covetics bulk and film.
- To perform Density Functional Theory calculations to obtain the equilibrium structure of covetics.

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Outline[&]

Bulk covetics

- Comparison of the structure of bulk Ag, Al alloys and Cu covetics
 - · XRD, TEM, SEM, DFT
- Incorporation of C in bulk Ag, Al and Cu covetic
 - Evidence of *sp2* bonding -- Raman, EELS, DFT
- · Properties of bulk Ag, Al and Cu covetic
 - · electrical measurements of Ag covetic

Film covetics

- · E-beam deposition of Cu covetic films
 - Structure
 - Resistivity
 - Transmittance
- · PLD deposition of Cu cv films
 - · XRD, SEM
- & All samples in this study were converted to covetics by Third Millennium Materials, LLC.

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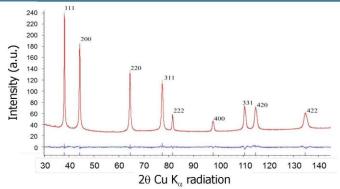
Structure of Bulk Ag Covetic

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DARPA

Structure of Bulk Ag Covetic



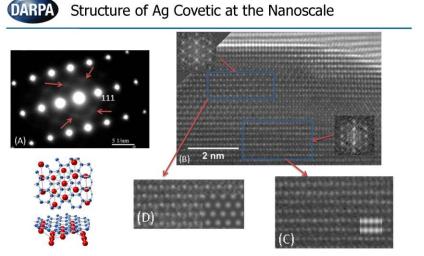
Experimental (blue) and Rietveld fitting (red) from powder Ag cv 6% (36.44 at %)

Difference (purple) with theoretical positions of the peaks for Ag.

- · No peaks for any allotrope of carbon are observed.
- Lattice constant of Ag cv 6% a=0.40877(1) nm lattice expansion of~0.05% compared to Ag metal.
- Preferential texture along <111>.

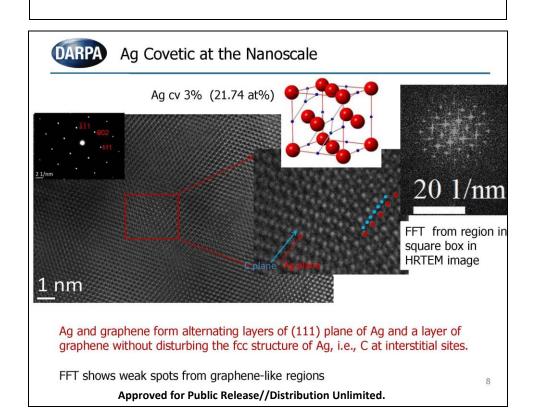
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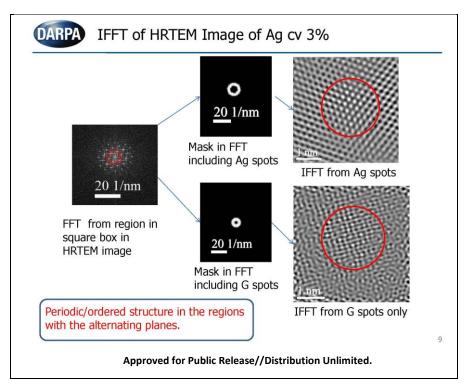
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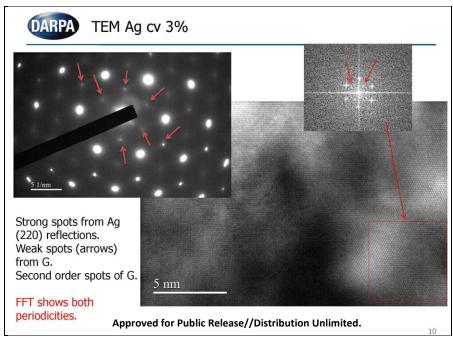


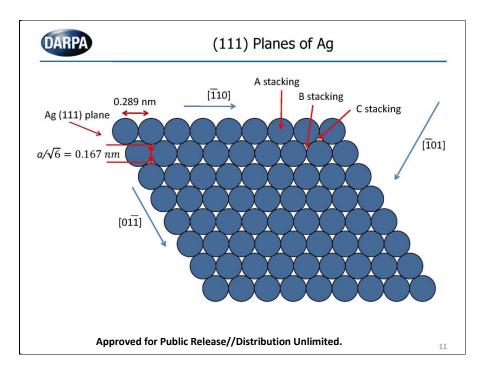
- Strong spots in (A) correspond to $[11\overline{2}]$ zone axis of Ag.
- Weak and broad spots in (A) correspond to $< 2\overline{1}\overline{1}0 >$ spots of graphite
- HRTEM image in (C) and computer image simulation of [112] plane of Ag.
- · HRTEM image in (D) and computer image simulation of graphene.

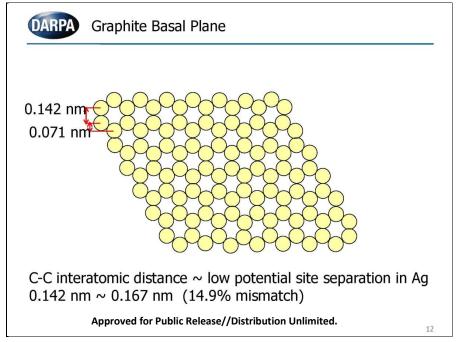
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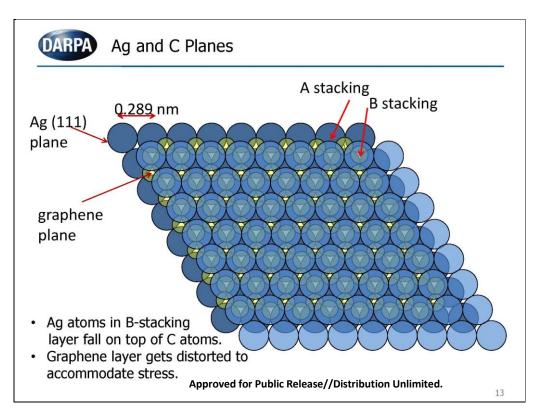


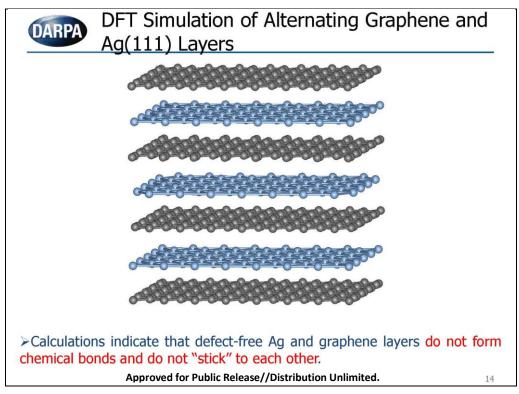


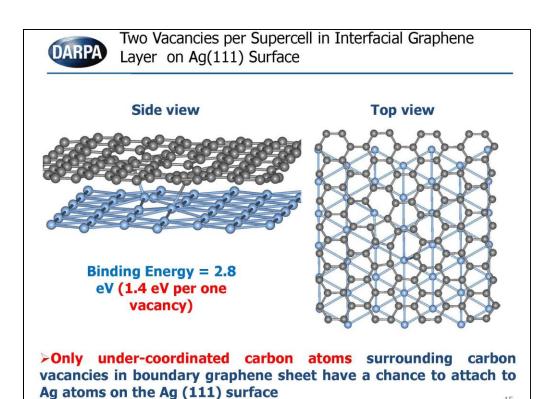


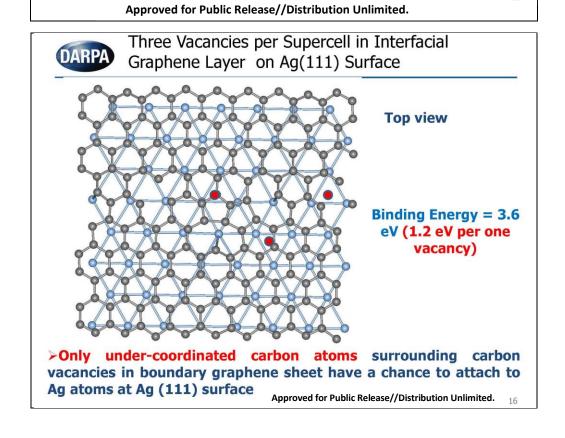










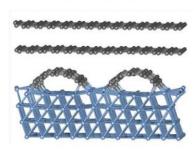




Several Rows of C Vacancies at Boundary Graphene Layer (Graphene Ribbons)

Initial Structure 0-01-00-00-00-00-00-00-00-00

Relaxed Structure



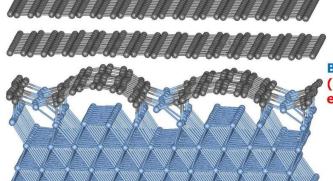
- Other structures (combined vacancy rows with single vacancies; defects at Ag surface, etc.) also show bonding between Ag and C.
- Bending of the graphene ribbon at the edges.

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Two Rows of Vacancies per Supercell in Boundary Graphene Layer on Ag(111) Surface (graphene ribbons)



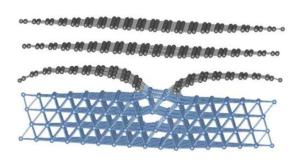
Binding Energy = 17 eV (1.4 eV per one "ribbon edge" atom)

>Only under-coordinated carbon atoms positioned along the edges of ribbons in boundary graphene sheet have a chance to attach to Ag atoms at Ag (111) surface

>Surface Ag atoms may leave the Ag surface and go to the edges of graphene ribbons, i.e., at the interface both Ag and C layers undergo serious reconstruction! Approved for Public Release//Distribution Unlimited.



DFT: Graphene in Ag Covetic



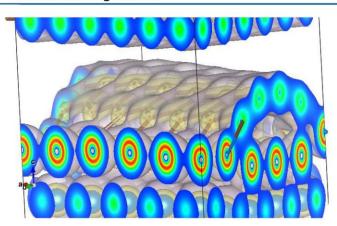
- Wider graphene ribbons have flatter surfaces.
- Bonding between Ag and C occurs at edges of ribbons.

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Nature of Chemical Bonding Between Graphene Layer and Surface Ag Atoms



>Only under-coordinated carbon atoms positioned around vacancy and/or at the edges of graphene ribbons attach to Ag atoms.

>Analysis indicates that C-Ag bond is a typical covalent bond (common electronic orbitals formation) similar to C-H bonds in hydrocarbons.

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Structure of Bulk Al Covetic

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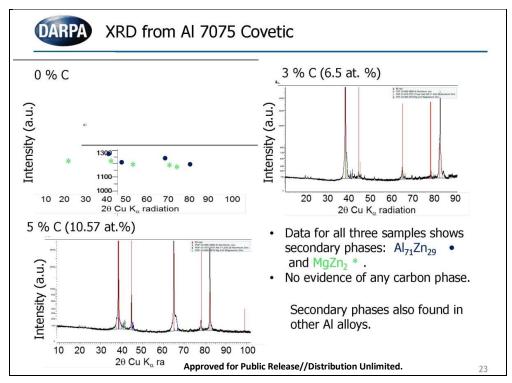
Al Alloys

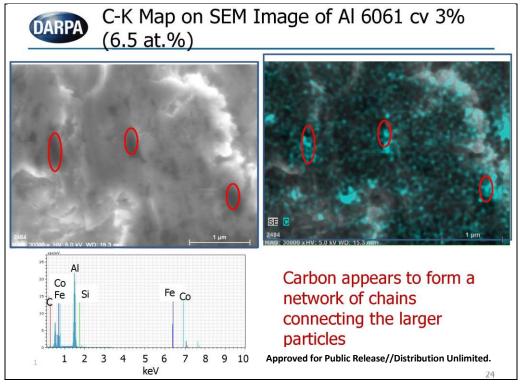
As-extruded Al 6061 As-extruded Al 6061 cv 3% (6.5 at%)

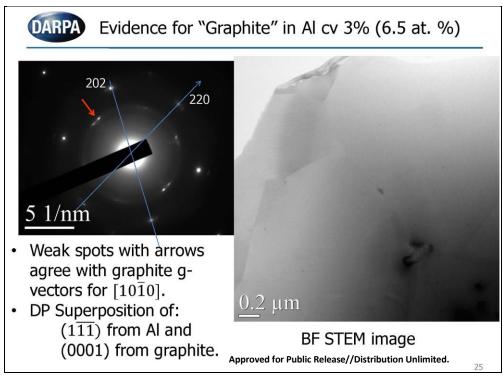
Al 7075 cv 3% and 5% (10.57 at%)

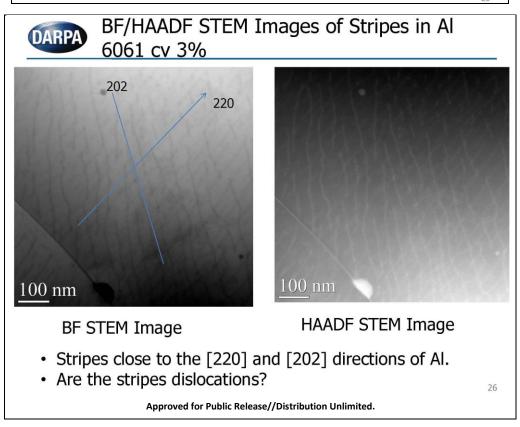
Al 5083 cv 2% (4.37 at.%) with 0, 2.5, 5, 7.5, 10 and 15% cold rolling.

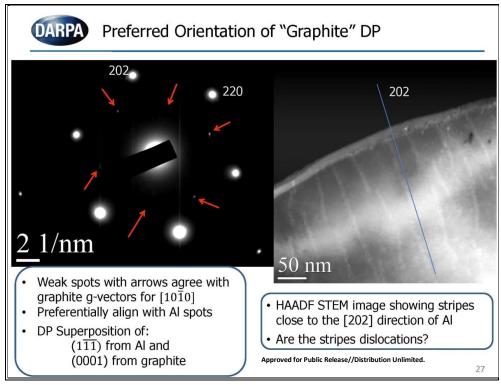
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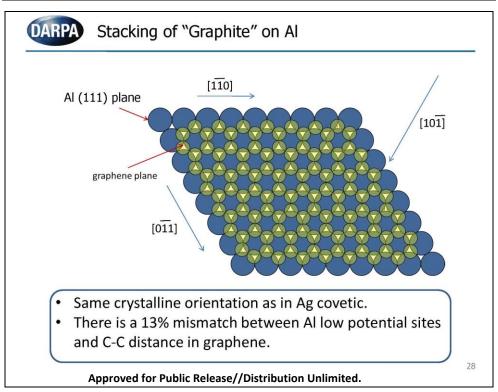


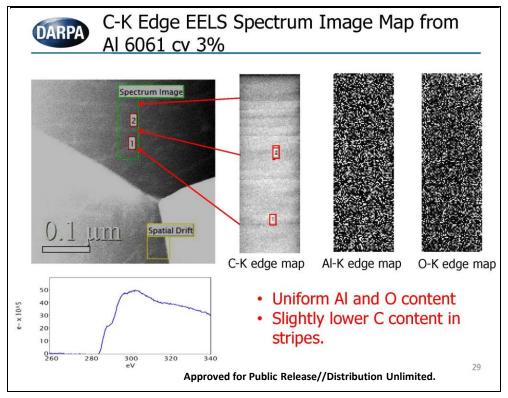


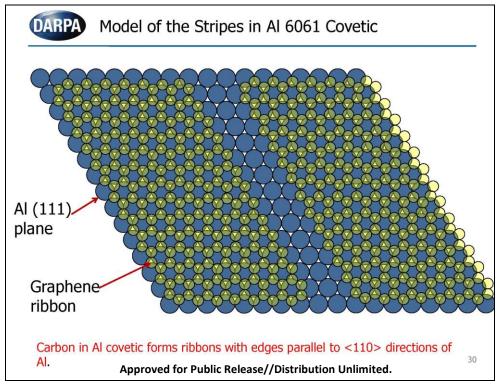










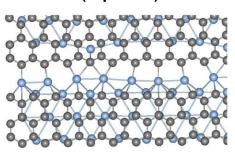




DFT of Aluminum Covetic

AIC (side view)

AIC (top view)



- Bonds between Al and C at edges of ribbon and vacancies in the graphene.
- Each C atom can bond to two or three Al atoms.
- Some Al atoms move to the graphene layer.

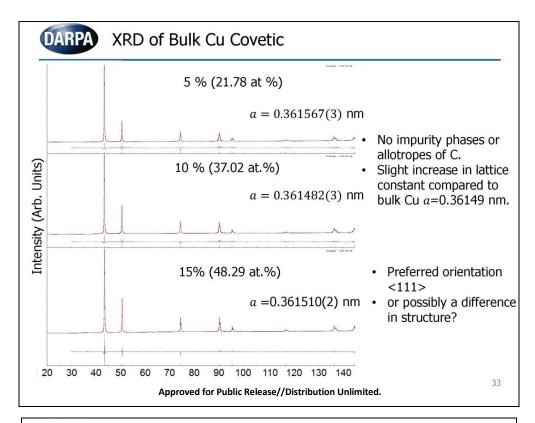
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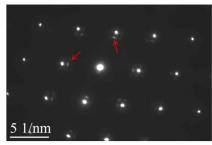
Structure of Bulk Cu Covetic

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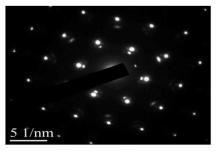




Modulation in Copper Covetic at the Nanoscale



Cu cv 2% (9.75 at. %)



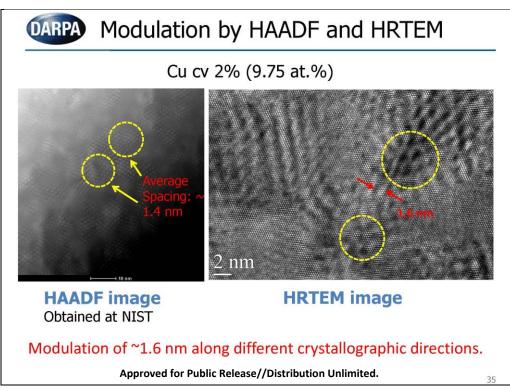
Cu cv 5% (21.78 at. %)

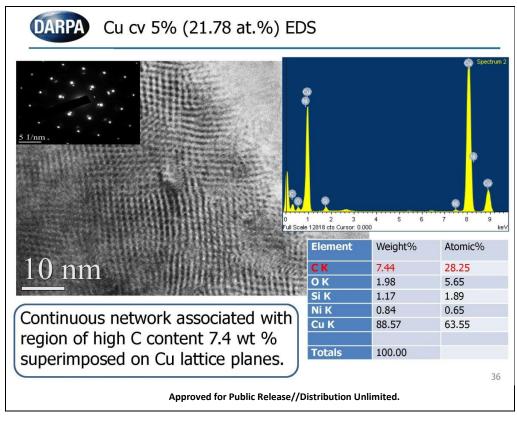
(110) Diffraction patterns.

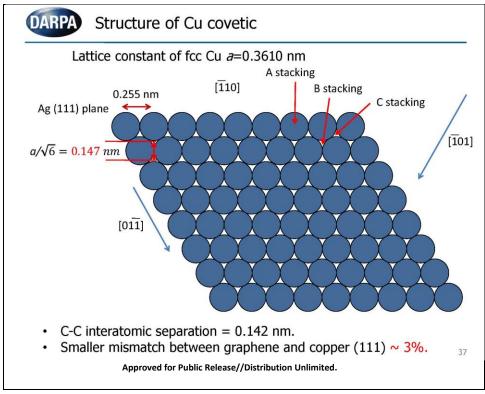
Weak spots are observed corresponding to a modulation of $^{\sim}1.6$ nm. The weak spots are stronger for the Cu cv 5% C.

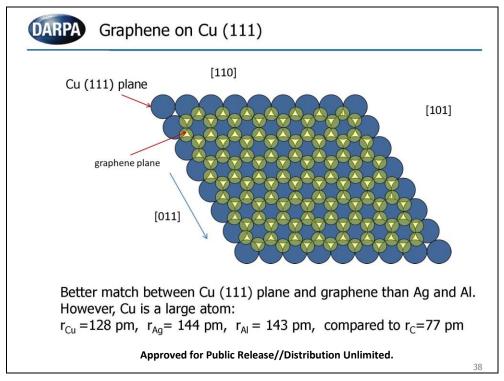
What is the origin of the weak spots?

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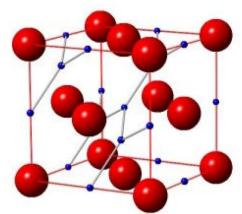








Distances in the fcc Unit Cells of Ag, Al and Cu Covetics



 r_{Cu} =128 pm, r_{Ag} = 144 pm, r_{AI} = 143 pm r_{C} =77 pm

$$d_{Ag-C} = \frac{a}{2} - r_{Ag} - r_{C} = -0.0165 \text{ nm}$$

$$d_{Al-C} = -0.0175 \text{ nm}$$

$$d_{Cu-C} = -0.0245 \text{ nm}$$

There is less space to accommodate C in Cu than in Ag or Al.

What is a model for the structure of Cu covetic?

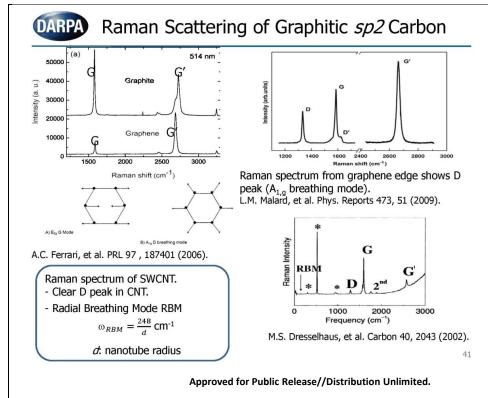
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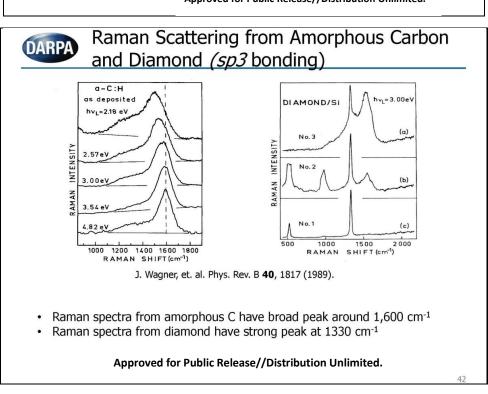
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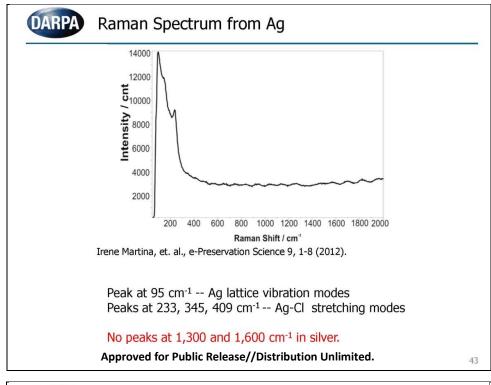


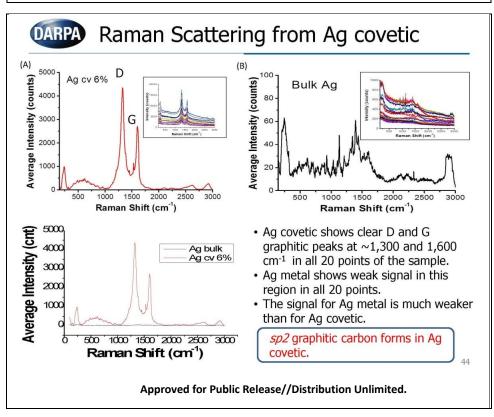
Evidence of *sp2* Carbon in Covetics: Raman Scattering

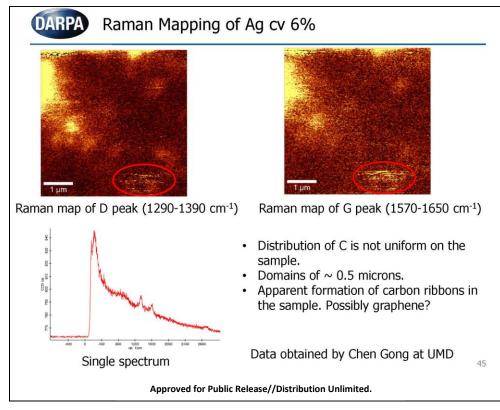
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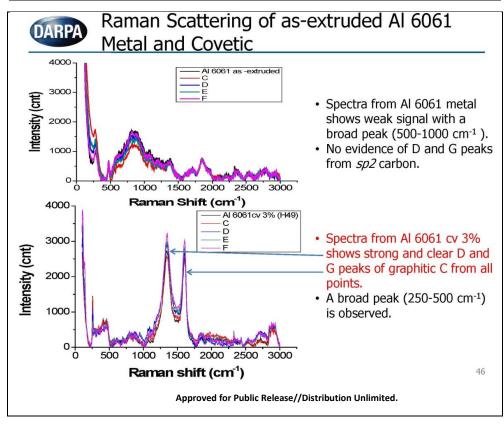


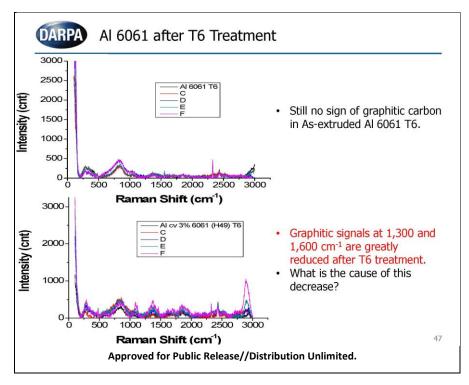


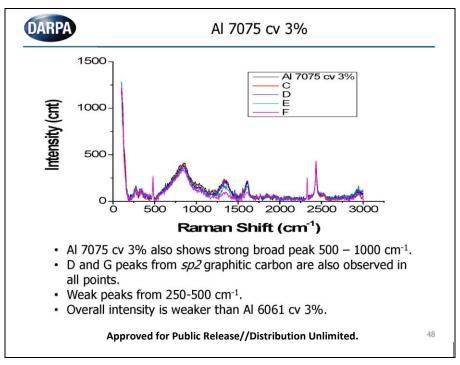


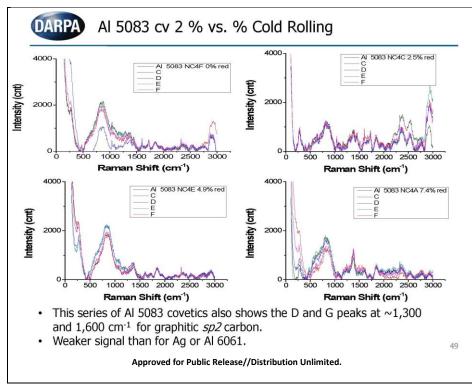


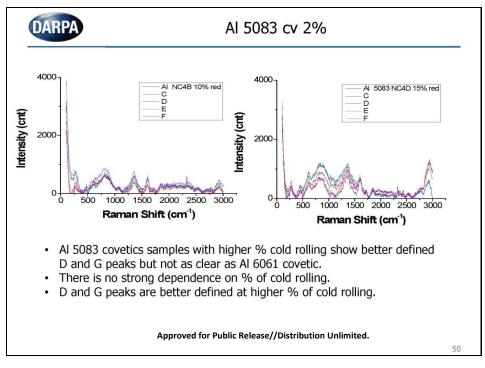


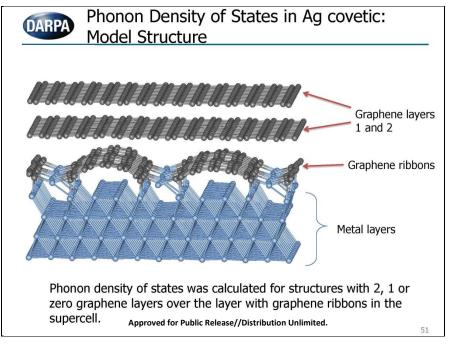


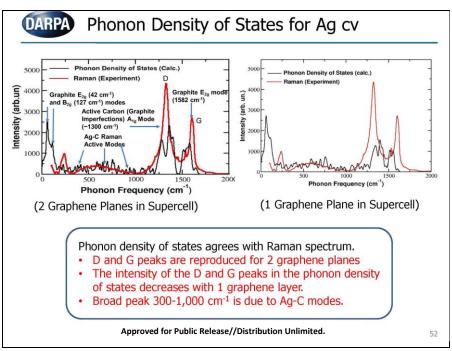


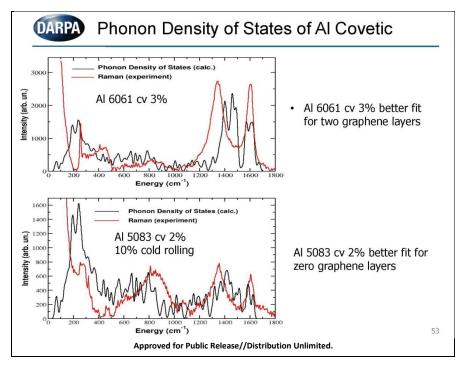


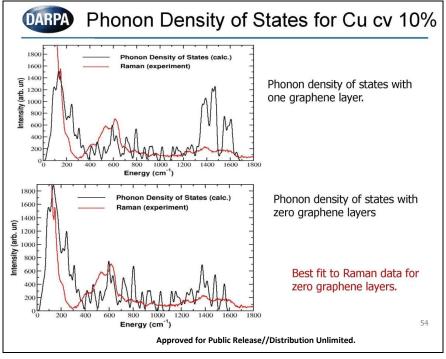


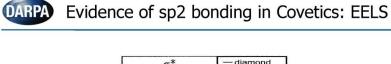


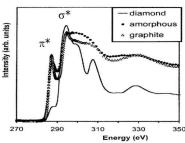










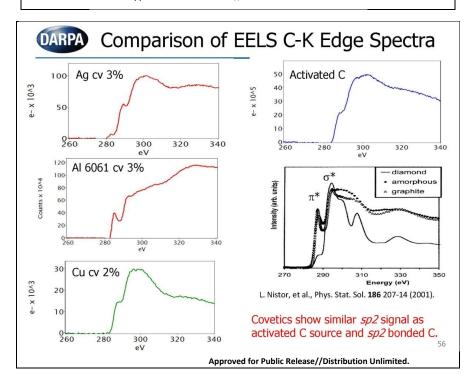


L. Nistor, et al., Phys. Stat. Sol. 186 207-14 (2001).

C-K edge:

- Feature at 284 eV corresponding to excitation of 1s electron to π^* antibonding unoccupied orbital.
- Feature at ~290 eV corresponds to transitions to σ^* state.
- Clear difference in the signal from carbon with different bonding (sp2 or sp3).

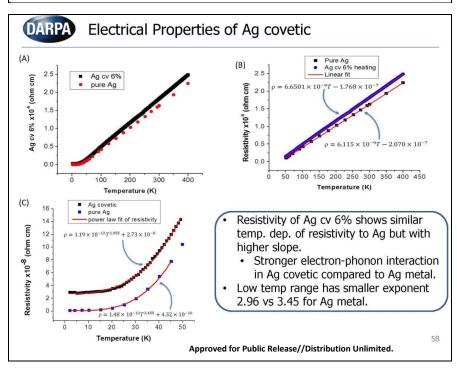
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Electrical Properties of Ag Covetic

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Temperature Dep. of Resistivity of Metals

Bloch-Grüneisen Formula for the resistivity of a pure

$$\rho(T) = \rho_o + \frac{C}{M\theta} \left(\frac{T}{\theta}\right)^5 \int_0^{\theta/T} \frac{z^5 e^z}{(e^z - 1)^2} dz$$

$$\rho_i(T) \rightarrow 124.431 \frac{c}{M\theta} \left(\frac{T}{\theta}\right)^5 \text{ as T} \rightarrow 0$$

$$\rho_i(T) \rightarrow 124.431 \frac{c}{M\theta} \left(\frac{T}{\theta}\right)^3 \text{ as } T \rightarrow 0$$

 $\rho_i(T) \rightarrow \frac{c}{4M\theta} \left(\frac{T}{\theta}\right) \text{ as } T \rightarrow \infty$

C: constant of the metal,

T: temperature

θ: characteristic temp. "electrical resistivity Debye Temp."

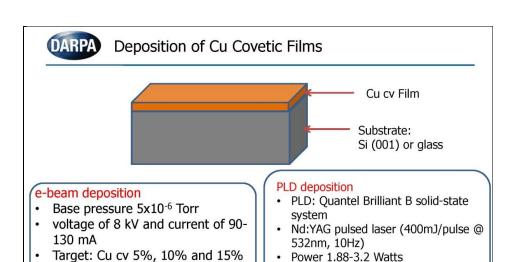
M: atomic weight

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Cu Covetic Thin Films

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Substrate: Si (001) and glass

Thickness 10-200 nm

Substrate temp: 25 °C and 350 °C

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Pressure: 10-2-2 Torr, Nitrogen and Ar

Substrate Temp: 150, 350 °C

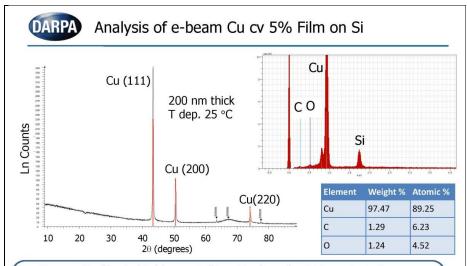
Target prep: 1 min ablation

Target: Cu cv 4%



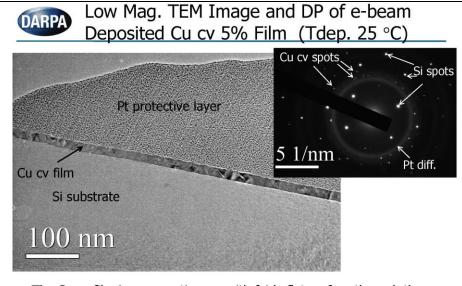
e-Beam Films

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- Cu covetic film is highly crystalline. Preferred <111> orientation.
- No Copper oxide phases are observed.
- · No C phases in the XRD pattern.
- · C is transferred to the film.
- C incorporation in the film is lower than the target used for deposition.

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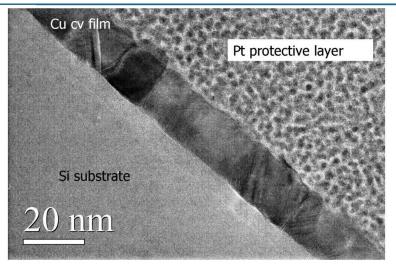


- The Cu cv film is very continuous with fairly flat surface through the whole TEM sample ~ 5 microns.
- The DP shows strong spots from Si substrate, weak spots from Cu cv film and broad ring from Pt protective layer.

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Thickness of Cu cv Film



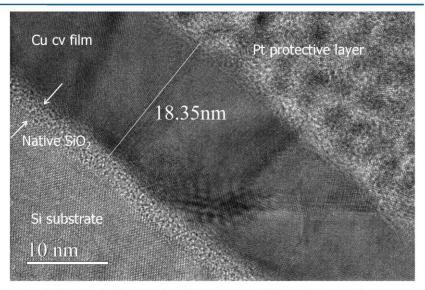
At higher magnification we see slight roughness of the film surface and polycrystallinity of the film with columnar structure.

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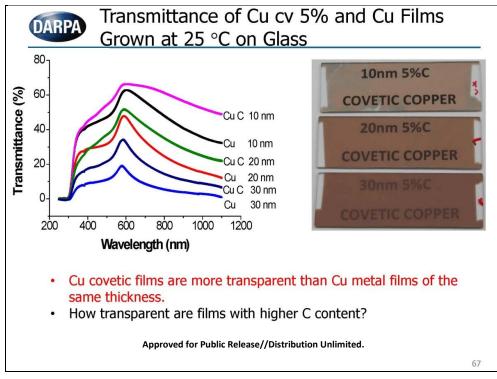
DARPA

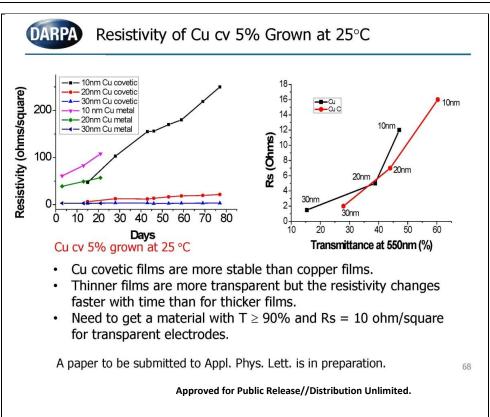
Cu cv 5% Film Thickness

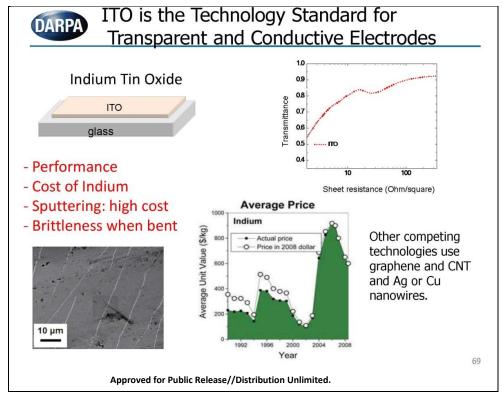


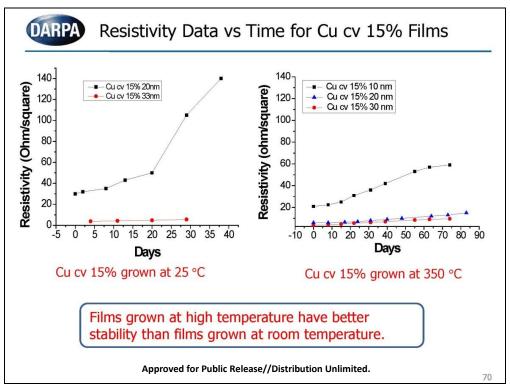
Film thickness fairly regular. Grains extend from SiO₂ to film surface.

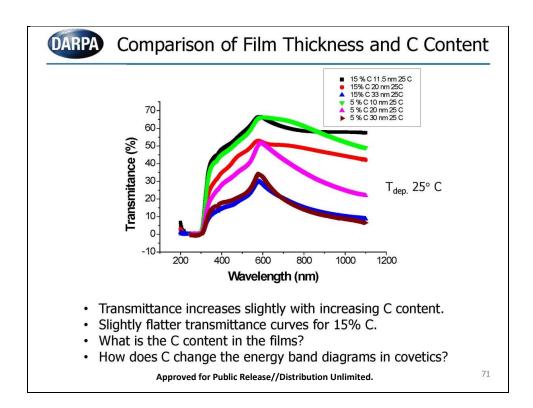
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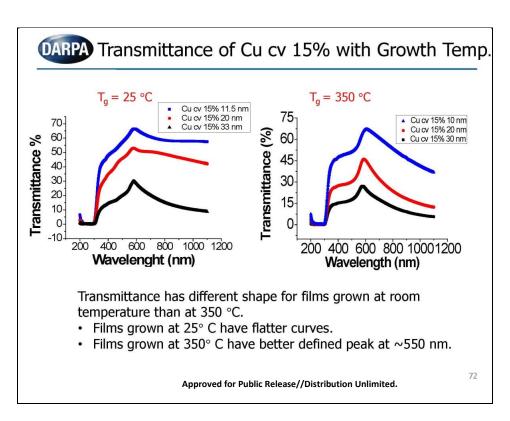


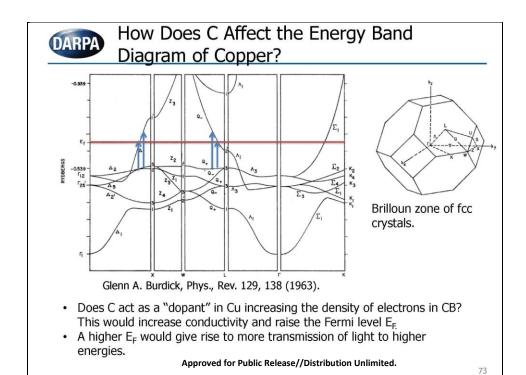












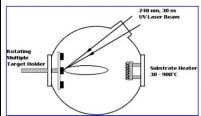


PLD of Cu cv Films

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Sample Deposition Specification



Advantages:

- Simple, flexible
- Multiple target possible
- Congruent evaporation
- Fast response
- Energetic evaporants

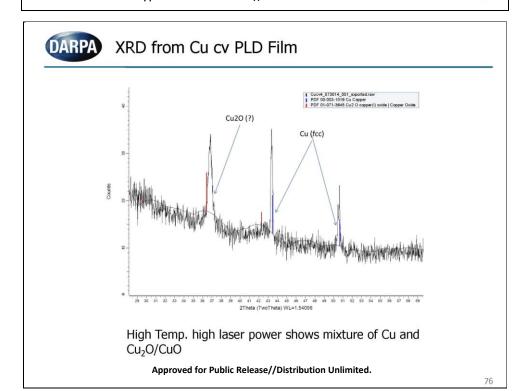
Disadvantages:

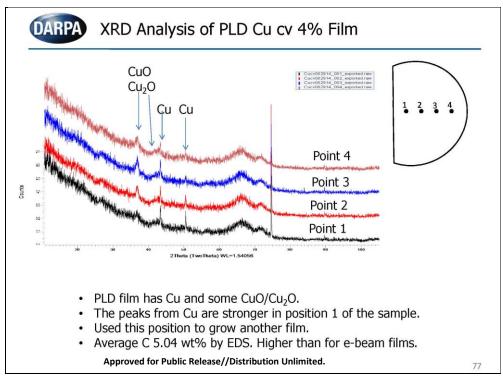
- micron-sized particles
- narrow forward angular distribution

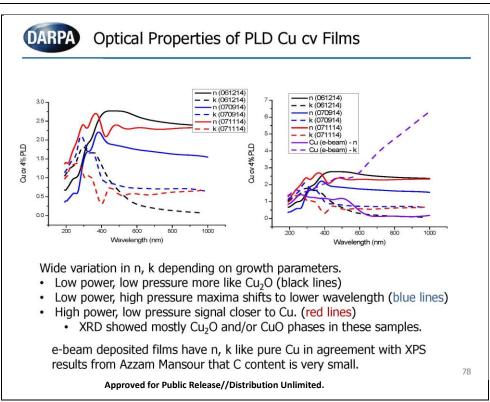
Date Grown	06/12// 14	07/09/14	07/11/1 4	07/30/14	08/29/1	09/18/14
Substrate	Si (100)	Si (100)	Si (100)	Si (100)	Si (100)	Si (100)
Laser Power (W)	1.93	1.8	3.55	3.3	3.2	3.2
Pressure (Torr)	1.00E-01	1.8	1.10E-01	1.00E-01	1.00E-01	9.50E-02
Substrate Temp. (°C)	150	150	150	350	350	150
Deposition time (mins)	15	15	21	64	64	60
Approx. Thickness (nm)	9.52	2.73	11.28	20.17	13.53	12.95
C content - EDS (%wt)				0.42	5.04	3.23

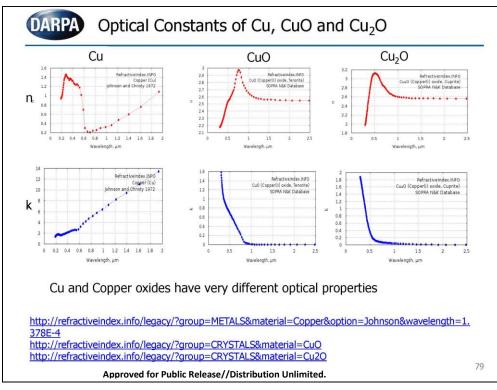
Film thickness estimated from n&k assuming values for Cu.

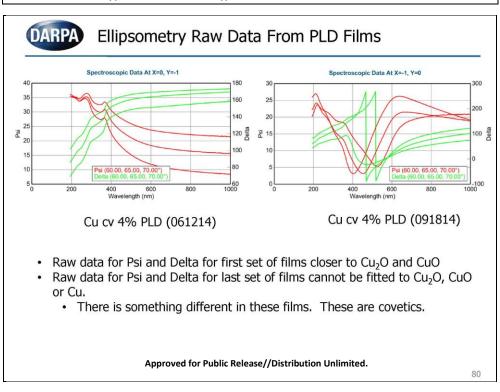
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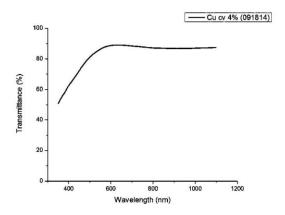








Transmittance of PLD Cu cv 4% Film



- 10 nm film, 3.23 % C by EDS
- Electrical resistivity too high in this film (film seems not to be continuous)

PLD seems to be a promising film deposition technique to transfer the carbon in covetics, but more work is necessary.

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Conclusions

- Carbon in Ag and Al covetic forms ribbons or layers of sp2 bonded carbon with a 3D epitaxial relationship with the Ag lattice.
 - · Evidence of 3D epitaxy from TEM
 - Evidence of sp2 bonding from Raman and EELS
- Covalent bonding between C and Ag or Al is predicted from DFT at edges of ribbons and C vacancies.
- Phonon density of states predicts M-C (M= Ag, Al and Cu) vibrational modes observed in Raman spectra of Ag and Al covetics.
- T6 treatment decreased the Raman signal of sp2 C in Al 6061 covetic.
- Cu covetic shows different structure than Ag and Al covetic. A modulated structure is characteristic of regions containing high C content.
- · Ag covetic shows stronger dependence of resistivity with temperature than Ag metal.
- · PLD of Cu covetic films produced films with higher C content than e-beam films.
- · Cu covetic films are more transparent than Cu films of same thickness
- Cu covetic films show higher environmental stability than Cu films

Papers in preparation.

- L. Salamanca-Riba, et. al., "Three Dimensional Epitaxy of Carbon Nanostructures in Silver," to be submitted to Adv. Functional Materials.
- R. Isaacs, et. al., "Nanocarbon-Copper Thin Film as Transparent Electrode," to be submitted to Appl. Phys. Lett.

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Thank you

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Lists of Symbols, Abbreviations, and Acronyms

Al aluminum

Ag silver

C carbon

Cu copper

DFT discrete Fourier transform

EELS electron energy loss spectroscopy

PLD pulsed laser deposition

TEM transmission electron microscopy

XRD X-ray diffraction

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